

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of ) ATOMIC LAYER DEPOSITION  
Hwang et al. ) METHOD AND SEMICONDUCTOR  
Application No. ) DEVICE FABRICATING  
Filing Date: ) APPARATUS HAVING ROTATABLE  
 ) GAS INJECTORS  
 ) Group Art Unit:  
 ) Examiner:

Commissioner for Patents  
P.O. Box 1450  
Mail Stop: Divisional Patent Application  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

Dear Sir:

Applicant hereby submits the following Preliminary Amendment to the above-referenced application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks begin on page 5 of this paper.